



ELECTRONIC COPY

LABORATORY GROWN DIAMOND REPORT

August 20, 2026	
IGI Report Number	LG826691992
Description	LABORATORY GROWN DIAMOND
Shape and Cutting Style	PRINCESS CUT
Measurements	8.84 X 8.51 X 6.23 MM

GRADING RESULTS

Carat Weight	4.03 CARATS
Color Grade	FANCY INTENSE YELLOW
Clarity Grade	VS 1

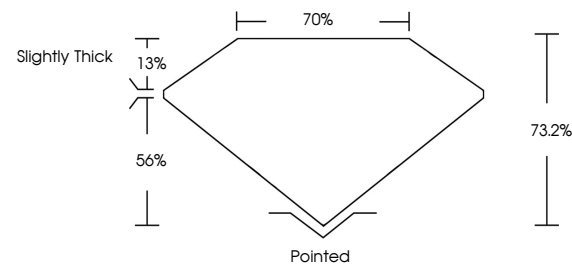
ADDITIONAL GRADING INFORMATION

Polish	EXCELLENT
Symmetry	EXCELLENT
Fluorescence	NONE
Inscription(s)	131 LG826691992

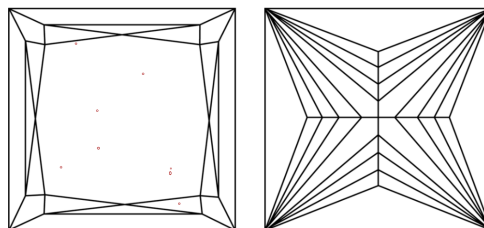
Comments: This Laboratory Grown Diamond was created by Chemical Vapor Deposition (CVD) growth process.

LG826691992
Report verification at igi.org

PROPORTIONS

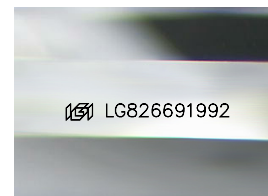


CLARITY CHARACTERISTICS



KEY TO SYMBOLS

Red symbols indicate internal characteristics.
Green symbols indicate external characteristics.



Sample Image Used

COLOR

D E F G H I J Faint Very Light Light

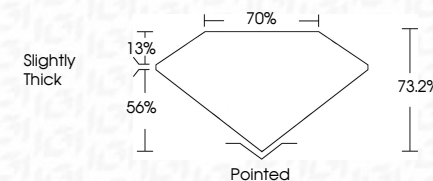
CLARITY

FL	IF	VVS ¹⁻²	VS ¹⁻²	SI ¹⁻²	I ¹⁻³
Flawless	Internally Flawless	Very Very Slightly Included	Very Slightly Included	Slightly Included	Included

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www.igi.org

August 20, 2026
GI Report No LG826691992

4.03 CARATS	VS 1	Slightly Thick	Pointed
4.03 CARATS	73.2%		EXCELLENT
FANCY INTENSE YELLOW	70%		EXCELLENT
			NONE

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